

<b>Search Notes</b> 	<b>Application/Control No.</b>	<b>Applicant(s)/Patent under Reexamination</b>	
	10/659,431	PARK, GEUN-YONG	
	<b>Examiner</b>	<b>Art Unit</b>	
	Hai C. Pham	2861	

INTERFERENCE SEARCHED			
Class	Subclass	Date	Examiner